

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Alexander Tregub et al. Art Unit: 1711  
Serial No.: 10/799,928 Examiner: N. Nutter  
Filed : March 12, 2004  
Assignee : Intel Corporation  
Title : USE OF ALTERNATIVE POLYMER MATERIALS FOR "SOFT"  
POLYMER PELLICLES

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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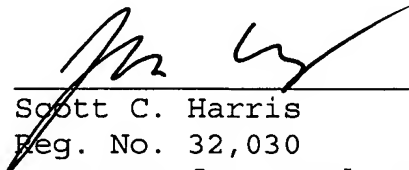
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Kindly accept this Information Disclosure Statement under Rule 97(c)(2). Please apply the rule 17(p) certification fee in the amount of \$180 to Deposit Account No. 06-1050.

Respectfully submitted,

Date: August 4, 2006

  
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Scott C. Harris  
Reg. No. 32,030  
Attorney for Intel Corporation

Fish & Richardson P.C.  
USPTO Customer No. 20985  
12390 El Camino Real  
San Diego, CA 92130  
Telephone: (858) 678-5070  
Facsimile: (858) 678-5099

BY  
JOHN F. CONROY  
REG. NO. 45,485

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|--|--|---------------------------------------|-------------------------------|
| Substitute Form PTO-1449<br>(Modified)   | U.S. Department of Commerce<br>Patent and Trademark Office | Attorney's Docket No.<br>10559-895001 | Application No.<br>10/799,928 |
| <b>Information Disclosure Statement<br/>by Applicant</b><br>(Use several sheets if necessary)<br>(37 CFR §1.98(b)) |  | Applicant<br>Alexander Tregub et al.  |                               |
|  |  | Filing Date<br>March 12, 2004         | Group Art Unit<br>1711        |

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| Examiner Initial | Desig. ID | Document Number | Publication Date | Patentee         | Class | Subclass | Filing Date If Appropriate |
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| Examiner Signature   | Date Considered |
| EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. |                 |

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| Examiner<br>Initial   | Desig.<br>ID | Document  |
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